



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Appln. No.: 10/736,230 Confirmation No.: 3133  
Applicant: LEVASIER et al.  
Filed: December 16, 2003  
Art Unit: 2851  
Examiner: TBA  
Docket No.: 081468-0307255  
Title: Lithographic Apparatus with Alignment Subsystem, Device Manufacturing Method, and Device Manufactured Thereby

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to the examination on the merits of the application submitted herewith, the Applicants respectfully request entry of this Preliminary Amendment to the above application as follows: